

INTERNATIONAL STANDARD

NORME INTERNATIONALE



**Semiconductor devices – Mechanical and climatic test methods –
Part 44: Neutron beam irradiated single event effect (SEE) test method for
semiconductor devices**

**Dispositifs à semiconducteurs – Méthodes d'essais mécaniques et climatiques –
Partie 44: Méthode d'essai des effets d'un événement isolé (SEE) irradié par un
faisceau de neutrons pour des dispositifs à semiconducteurs**



THIS PUBLICATION IS COPYRIGHT PROTECTED

Copyright © 2016 IEC, Geneva, Switzerland

All rights reserved. Unless otherwise specified, no part of this publication may be reproduced or utilized in any form or by any means, electronic or mechanical, including photocopying and microfilm, without permission in writing from either IEC or IEC's member National Committee in the country of the requester. If you have any questions about IEC copyright or have an enquiry about obtaining additional rights to this publication, please contact the address below or your local IEC member National Committee for further information.

Droits de reproduction réservés. Sauf indication contraire, aucune partie de cette publication ne peut être reproduite ni utilisée sous quelque forme que ce soit et par aucun procédé, électronique ou mécanique, y compris la photocopie et les microfilms, sans l'accord écrit de l'IEC ou du Comité national de l'IEC du pays du demandeur. Si vous avez des questions sur le copyright de l'IEC ou si vous désirez obtenir des droits supplémentaires sur cette publication, utilisez les coordonnées ci-après ou contactez le Comité national de l'IEC de votre pays de résidence.

IEC Central Office
3, rue de Varembe
CH-1211 Geneva 20
Switzerland

Tel.: +41 22 919 02 11
Fax: +41 22 919 03 00
info@iec.ch
www.iec.ch

About the IEC

The International Electrotechnical Commission (IEC) is the leading global organization that prepares and publishes International Standards for all electrical, electronic and related technologies.

About IEC publications

The technical content of IEC publications is kept under constant review by the IEC. Please make sure that you have the latest edition, a corrigenda or an amendment might have been published.

IEC Catalogue - webstore.iec.ch/catalogue

The stand-alone application for consulting the entire bibliographical information on IEC International Standards, Technical Specifications, Technical Reports and other documents. Available for PC, Mac OS, Android Tablets and iPad.

IEC publications search - www.iec.ch/searchpub

The advanced search enables to find IEC publications by a variety of criteria (reference number, text, technical committee,...). It also gives information on projects, replaced and withdrawn publications.

IEC Just Published - webstore.iec.ch/justpublished

Stay up to date on all new IEC publications. Just Published details all new publications released. Available online and also once a month by email.

Electropedia - www.electropedia.org

The world's leading online dictionary of electronic and electrical terms containing 20 000 terms and definitions in English and French, with equivalent terms in 15 additional languages. Also known as the International Electrotechnical Vocabulary (IEV) online.

IEC Glossary - std.iec.ch/glossary

65 000 electrotechnical terminology entries in English and French extracted from the Terms and Definitions clause of IEC publications issued since 2002. Some entries have been collected from earlier publications of IEC TC 37, 77, 86 and CISPR.

IEC Customer Service Centre - webstore.iec.ch/csc

If you wish to give us your feedback on this publication or need further assistance, please contact the Customer Service Centre: csc@iec.ch.

A propos de l'IEC

La Commission Electrotechnique Internationale (IEC) est la première organisation mondiale qui élabore et publie des Normes internationales pour tout ce qui a trait à l'électricité, à l'électronique et aux technologies apparentées.

A propos des publications IEC

Le contenu technique des publications IEC est constamment revu. Veuillez vous assurer que vous possédez l'édition la plus récente, un corrigendum ou amendement peut avoir été publié.

Catalogue IEC - webstore.iec.ch/catalogue

Application autonome pour consulter tous les renseignements bibliographiques sur les Normes internationales, Spécifications techniques, Rapports techniques et autres documents de l'IEC. Disponible pour PC, Mac OS, tablettes Android et iPad.

Recherche de publications IEC - www.iec.ch/searchpub

La recherche avancée permet de trouver des publications IEC en utilisant différents critères (numéro de référence, texte, comité d'études,...). Elle donne aussi des informations sur les projets et les publications remplacées ou retirées.

IEC Just Published - webstore.iec.ch/justpublished

Restez informé sur les nouvelles publications IEC. Just Published détaille les nouvelles publications parues. Disponible en ligne et aussi une fois par mois par email.

Electropedia - www.electropedia.org

Le premier dictionnaire en ligne de termes électroniques et électriques. Il contient 20 000 termes et définitions en anglais et en français, ainsi que les termes équivalents dans 15 langues additionnelles. Egalement appelé Vocabulaire Electrotechnique International (IEV) en ligne.

Glossaire IEC - std.iec.ch/glossary

65 000 entrées terminologiques électrotechniques, en anglais et en français, extraites des articles Termes et Définitions des publications IEC parues depuis 2002. Plus certaines entrées antérieures extraites des publications des CE 37, 77, 86 et CISPR de l'IEC.

Service Clients - webstore.iec.ch/csc

Si vous désirez nous donner des commentaires sur cette publication ou si vous avez des questions contactez-nous: csc@iec.ch.

INTERNATIONAL STANDARD

NORME INTERNATIONALE



**Semiconductor devices – Mechanical and climatic test methods –
Part 44: Neutron beam irradiated single event effect (SEE) test method for
semiconductor devices**

**Dispositifs à semiconducteurs – Méthodes d'essais mécaniques et climatiques –
Partie 44: Méthode d'essai des effets d'un événement isolé (SEE) irradié par un
faisceau de neutrons pour des dispositifs à semiconducteurs**

INTERNATIONAL
ELECTROTECHNICAL
COMMISSION

COMMISSION
ELECTROTECHNIQUE
INTERNATIONALE

ICS 31.080.01

ISBN 978-2-8322-3541-6

**Warning! Make sure that you obtained this publication from an authorized distributor.
Attention! Veuillez vous assurer que vous avez obtenu cette publication via un distributeur agréé.**

CONTENTS

FOREWORD.....	4
1 Scope.....	6
2 Normative references.....	6
3 Terms and definitions	6
4 Test apparatus	9
4.1 Measurement equipment	9
4.2 Radiation source	10
4.3 Test sample	10
5 Procedure neutron irradiated soft error test	10
5.1 Surface preparation.....	10
5.2 Power supply voltage	10
5.3 Ambient temperature.....	11
5.4 Core cycle time	11
5.5 Data pattern.....	11
5.6 Number of measurement samples.....	11
5.7 Calculations for time required in the beam	11
6 Evaluation	11
6.1 Measurement and failure rate estimation	11
6.2 Determination of MCU and MBU cross sections	12
6.3 Determination of device FIT (event rate) from cross section	12
7 Summary.....	12
Annex A (informative) Additional information for the applicable procurement specification	13
A.1 General.....	13
A.2 Description of the beam source	13
A.3 Description of the sample and test vehicle	13
A.3.1 Sample size	13
A.3.2 Vehicle description.....	13
A.4 Test description	14
A.5 Test results	14
Annex B (informative) White neutron test apparatus	16
Annex C (informative) Failure rate calculation.....	18
C.1 An influence of soft error for actual semiconductor devices	18
C.1.1 General	18
C.1.2 Duty derating	18
C.1.3 Utility derating.....	18
C.1.4 Critically derating	19
C.2 Failure rate calculation including derating	19
Bibliography	20
Figure B.1 – Typical white neutron spectra with different shield (polyethylene) thickness	16
Figure B.2 – Typical neutron spectrum	17
Figure B.3 – Comparison of LANSCE (WNR) and TRIUMF neutron spectra with terrestrial neutron spectrum	17

Figure C.1 – Schematic image of duty derating.....	18
Figure C.2 – Schematic image of memory effective area for utility derating	19

iTeh STANDARD PREVIEW
(standards.iteh.ai)

[IEC 60749-44:2016](https://standards.iteh.ai/catalog/standards/sist/cad3fc11-37a6-4eb5-91e8-152b49a5ada0/iec-60749-44-2016)

<https://standards.iteh.ai/catalog/standards/sist/cad3fc11-37a6-4eb5-91e8-152b49a5ada0/iec-60749-44-2016>

INTERNATIONAL ELECTROTECHNICAL COMMISSION

SEMICONDUCTOR DEVICES –
MECHANICAL AND CLIMATIC TEST METHODS –

**Part 44: Neutron beam irradiated single event effect (SEE)
test method for semiconductor devices**

FOREWORD

- 1) The International Electrotechnical Commission (IEC) is a worldwide organization for standardization comprising all national electrotechnical committees (IEC National Committees). The object of IEC is to promote international co-operation on all questions concerning standardization in the electrical and electronic fields. To this end and in addition to other activities, IEC publishes International Standards, Technical Specifications, Technical Reports, Publicly Available Specifications (PAS) and Guides (hereafter referred to as "IEC Publication(s)"). Their preparation is entrusted to technical committees; any IEC National Committee interested in the subject dealt with may participate in this preparatory work. International, governmental and non-governmental organizations liaising with the IEC also participate in this preparation. IEC collaborates closely with the International Organization for Standardization (ISO) in accordance with conditions determined by agreement between the two organizations.
- 2) The formal decisions or agreements of IEC on technical matters express, as nearly as possible, an international consensus of opinion on the relevant subjects since each technical committee has representation from all interested IEC National Committees.
- 3) IEC Publications have the form of recommendations for international use and are accepted by IEC National Committees in that sense. While all reasonable efforts are made to ensure that the technical content of IEC Publications is accurate, IEC cannot be held responsible for the way in which they are used or for any misinterpretation by any end user.
- 4) In order to promote international uniformity, IEC National Committees undertake to apply IEC Publications transparently to the maximum extent possible in their national and regional publications. Any divergence between any IEC Publication and the corresponding national or regional publication shall be clearly indicated in the latter.
- 5) IEC itself does not provide any attestation of conformity. Independent certification bodies provide conformity assessment services and, in some areas, access to IEC marks of conformity. IEC is not responsible for any services carried out by independent certification bodies.
- 6) All users should ensure that they have the latest edition of this publication.
- 7) No liability shall attach to IEC or its directors, employees, servants or agents including individual experts and members of its technical committees and IEC National Committees for any personal injury, property damage or other damage of any nature whatsoever, whether direct or indirect, or for costs (including legal fees) and expenses arising out of the publication, use of, or reliance upon, this IEC Publication or any other IEC Publications.
- 8) Attention is drawn to the Normative references cited in this publication. Use of the referenced publications is indispensable for the correct application of this publication.
- 9) Attention is drawn to the possibility that some of the elements of this IEC Publication may be the subject of patent rights. IEC shall not be held responsible for identifying any or all such patent rights.

International Standard IEC 60749-44 has been prepared by IEC technical committee 47: Semiconductor devices.

The text of this standard is based on the following documents:

FDIS	Report on voting
47/2303/FDIS	47/2312/RVD

Full information on the voting for the approval of this standard can be found in the report on voting indicated in the above table.

This publication has been drafted in accordance with the ISO/IEC Directives, Part 2.

A list of all the parts in the IEC 60749 series, published under the general title *Semiconductor devices – Mechanical and climatic test methods*, can be found on the IEC website.

The committee has decided that the contents of this publication will remain unchanged until the stability date indicated on the IEC website under "http://webstore.iec.ch" in the data related to the specific publication. At this date, the publication will be

- reconfirmed,
- withdrawn,
- replaced by a revised edition, or
- amended.

IMPORTANT – The 'colour inside' logo on the cover page of this publication indicates that it contains colours which are considered to be useful for the correct understanding of its contents. Users should therefore print this document using a colour printer.

iTeh STANDARD PREVIEW (standards.iteh.ai)

[IEC 60749-44:2016](#)

<https://standards.iteh.ai/catalog/standards/sist/cad3fc11-37a6-4eb5-91e8-152b49a5ada0/iec-60749-44-2016>

SEMICONDUCTOR DEVICES – MECHANICAL AND CLIMATIC TEST METHODS –

Part 44: Neutron beam irradiated single event effect (SEE) test method for semiconductor devices

1 Scope

This part of IEC 60749 establishes a procedure for measuring the single event effects (SEEs) on high density integrated circuit semiconductor devices including data retention capability of semiconductor devices with memory when subjected to atmospheric neutron radiation produced by cosmic rays. The single event effects sensitivity is measured while the device is irradiated in a neutron beam of known flux. This test method can be applied to any type of integrated circuit.

NOTE 1 Semiconductor devices under high voltage stress can be subject to single event effects including SEB, single event burnout and SEGR single event gate rupture, for this subject which is not covered in this document, please refer to IEC 62396-4 [2].

NOTE 2 In addition to the high energy neutrons some devices can have a soft error rate due to low energy (<1 eV) thermal neutrons. For this subject which is not covered in this document, please refer to IEC 62396-5 [3].

2 Normative references

The following documents, in whole or in part, are normatively referenced in this document and are indispensable for its application. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

None.

3 Terms and definitions

For the purposes of this document, the following terms and definitions apply.

3.1

critical charge

Q_{crit}

smallest charge that will cause a SEE if injected or deposited in the sensitive volume

3.2

single-event upset

SEU

in a semiconductor device when the radiation absorbed by the device is sufficient to change a cell's logic state

Note 1 to entry: After a new write cycle, the original state can be recovered.

3.3

multiple bit upset

MBU

energy deposited in the silicon of an electronic component by a single ionising particle causing more than one bit in the same word to be upset

Note 1 to entry: The definition of MBU has been updated due to the introduction of the definition of MCU.

3.4 multiple cell upset MCU

energy deposited in the silicon of an electronic component by a single ionising particle induces several bits in an integrated circuit (IC) to be upset at one time

3.5 soft error

erroneous output signal from a latch or memory cell that can be corrected by performing one or more normal functions of the device containing the latch or memory cell

Note 1 to entry: As commonly used, the term refers to an error caused by radiation or electromagnetic pulses and not to an error associated with a physical defect introduced during the manufacturing process.

Note 2 to entry: Soft errors can be generated from SEU, SEFI, MBU, MCU, and or SET. The term SER has been adopted by the commercial industry while the more specific terms SEU, SEFI, etc. are typically used by the avionics, space and military electronics communities.

Note 3 to entry: The term “soft error” was first introduced (for DRAMs and ICs) by May and Woods of Intel in their April 1978 paper at the IRPS and the term “single event upset” was introduced by Guenzer, Wolicki and Allas of NRL in their 1979 NSREC paper (SEU of DRAMs by neutrons and protons).

3.6 single event effect SEE

response of a component caused by the impact of a single energetic particle

Note 1 to entry: Examples of energetic particle include galactic cosmic rays, solar energetic particles, energetic neutrons and protons

Note 2 to entry: The range of responses can include both non-destructive (for example upset) and destructive (for example latch-up or gate rupture) phenomena.

3.7 single-event hard error SHE

single event induced hard error

irreversible change in operation from a single radiation event that is typically associated with permanent damage to one or more of the device elements

Note 1 to entry: Examples include permanently stuck-bit in the device and gate oxide rupture.

3.8 soft error, power cycle PCSE

soft error that is not corrected by repeated reading or writing but can be corrected by the removal of power

3.9 flux

<particle radiation> time rate of flow of particle energy emitted from or incident on a surface, divided by the area of that surface

Note 1 to entry: The flux is usually expressed in particles per square centimetre second (N/cm^2s) or particles per square centimetre hour (N/cm^2h).

3.10 soft error rate SER

rate at which soft errors are occurring

**3.11
failure in time****FIT**

failure in 10^9 device-hours

3.12**firm fault**

failure that cannot be reset other than by rebooting the system or by cycling the power to the relevant functional element

3.13**hard fault**

at the aircraft function level, permanent failure of a component within an LRU

Note 1 to entry: A hard fault results in the removal of the LRU affected and the replacement of the permanently damaged component before a system/system architecture can be restored to full functionality. Such a fault can impact the value for the MTBF of the LRU repaired.

3.14**single event burnout****SEB**

burnout of a powered electronic component or part thereof as a result of the energy absorption triggered by an individual radiation event

3.15**single event functional interrupt****SEFI**

occurrence of an upset, usually in a complex device, such that a control path is corrupted, leading the part to cease to function properly

Note 1 to entry: Examples of a complex device include microprocessors

Note 2 to entry: This effect has sometimes been referred to as lockup, indicating that sometimes the part can be put into a “frozen” state.

3.16**single event gate rupture****SEGR**

event in the gate of a powered insulated gate component when the radiation charge absorbed by the device is sufficient to cause gate rupture, which is destructive

3.17**single event latch up****SEL**

event in a four layer semiconductor device when the radiation absorbed by the device is sufficient to cause a node within the powered semiconductor device to be held in a fixed state whatever input is applied until the device is de-powered

Note 1 to entry: Such latch up can be destructive or non-destructive

3.18**single event transient****SET**

momentary voltage excursion (voltage spike) at a node in an integrated circuit caused by a single energetic particle strike

Note 1 to entry: The specific terms ASET analogue single event transient and DSET digital single event transient can be used.

3.19
analogue single event transient
ASET

spurious signal or voltage produced at the output of an analogue device by the deposition of charge by a single particle

3.20
digital single event transient
DSET

spurious digital signal or voltage, induced by the deposition of charge by a single particle that can propagate through the circuit path during one clock cycle

3.21
multiple bit upset
MBU

energy deposited in the silicon of an electronic component by a single ionising particle causing upset of more than one bit in the same word

3.22
cross section

σ
<radiation terms for particle interactions>

combination of a sensitive area and probability of an interaction depositing the critical charge for a SEE

The cross section (σ) is calculated using the following formula:

$$\sigma = N / \Phi$$

Where N, is the number of errors and Φ the particle fluence

Note 1 to entry: The units for cross section are cm² per device or per bit.

3.23
multiple-cell upset
MCU

event that induces several bits to fail at one time

Note 1 to entry: MCU consists of multiple-cell error bits which are usually but not always adjacent.

3.24
single bit upset
SBU

in a semiconductor device when the radiation absorbed by the device is sufficient to change a single cell's logic state

Note 1 to entry: After a new write cycle, the original state can be recovered.

4 Test apparatus**4.1 Measurement equipment**

The equipment shall be capable of measuring the functions of the integrated circuit devices, and capable of measuring the time taken for the change of stored data or other events by the exposure to energetic particles, such as neutrons, protons and alpha radiation to take place (i.e. the generation of a soft error). Alternatively, the test equipment (memory tester, etc.) shall have the capability of counting the number of soft errors in unit time. The equipment shall be capable of identifying when hard or firm faults occur; although these events are in general less frequent, their impact is higher.

NOTE The standard IEC 60749-38 contains a non-accelerated real-time soft error test.

4.2 Radiation source

In order to perform accelerated terrestrial SER measurements, a radiation source(s) is required that is similar to the energy spectrum of terrestrial cosmic rays. This can be accomplished by a broad spectrum beam or by using multiple mono-energetic beams. The radiation beam or beams should cover the whole spectrum of atmospheric radiation taking into account the energy differences in the various beams. Special attention is to be taken with respect to the effects of scattered radiation from the beam on the test setup. Technical personnel operating the facility are to be consulted in terms of the relative flux of the forward and backward scattering distribution of the beam. They shall also be consulted on effectiveness of shielding materials for the main beam and scattered beam attenuation. The number of boards in front of the device under test (DUT) and the distance from the counter shall be recorded to be used in attenuation calculations. The results of the testing shall be due to radiation effects on the DUT and not from interaction of radiation with other components in the test. In particular, power supplies can be vulnerable to radiation-induced avalanche breakdown. Sensitive electronic circuits in the tester and any device on the DUT board (e.g., buffers or registers) can also be affected. These components are to be moved as far from the primary and scattered beam as possible or appropriate shielding is to be used. Care is to be taken that the tester and power supply are not affected by scattered radiation from the beam before conducting tests in a new facility or before conducting tests with a new tester setup (including modified shielding of the tester). To assure this, the tester is to be positioned and shielded in exactly the same way as during actual tests except for the DUT that shall be positioned outside the beam or shielded from the beam. With the beam on and the DUT shielded or otherwise not exposed to the beam, test the DUT. Tester setup verification is successful if no failures are observed. Unless otherwise specified, this tester setup verification test shall last as long as a typical test. Care shall be taken to prevent upsets from stray signals or noise in the cables to the DUT. A tester readiness check shall be performed as part of the test sequence to assure electrical noise immunity.

[IEC 60749-44:2016](https://standards.iteh.ai/catalog/standards/sist/cad3fc11-37a6-4eb5-91e8-152b49a5ada0/iec-60749-44-2016)

4.3 Test sample

Any type of integrated circuits with memory can be tested. The device parameters (capacitance of the memory cell in the DRAM, etc.) which can affect the soft error rate shall be well understood. Modern complex devices including application specific integrated circuits (ASIC) and field programmable gate arrays (FPGA) can contain more than one type of memory. These can have very different radiation upset sensitivities. FPGA as an example will generally contain configuration memory, register (flip/flop) memory and composite SRAM memory. An ASIC for example generally contains register (flip/flop) memory and composite SRAM memory. It is important that the distinction is recognised between these elements and each of the SEE rates determined separately for each type of memory bit.

5 Procedure neutron irradiated soft error test

5.1 Surface preparation

The mould compound of the DUT does not need to be etched off because the range of neutron beam in the device is sufficiently long.

5.2 Power supply voltage

Unless otherwise required, the power supply voltage shall be the nominal operating conditions specified for the device.

In order to characterize cosmic ray sensitivity as a function of Q_{crit} (the minimum charge needed to upset a memory cell), lower and higher voltages are also permitted.

5.3 Ambient temperature

Unless otherwise required in any specification, the ambient temperature shall be the nominal operating conditions specified for the device.

5.4 Core cycle time

The core cycle time is dependent on the samples under test (when required, the core cycle time dependence shall be measured).

5.5 Data pattern

This is dependent on the samples under test. The structure of the data patterns shall be recorded (a checker board, all 0/1-read/write pattern, etc).

Record the impact of data patterns on the observed rates.

5.6 Number of measurement samples

Multiple samples shall be measured to take into account measurement variation. If test samples are mounted along the beam line with samples behind the first sample, the beam fluence shall be calculated at each test location allowing for beam attenuation at that sample. The maximum variation in flux between different parts in the sample shall not exceed 20 %.

5.7 Calculations for time required in the beam

Information shall be provided on how to calculate, to a specified accuracy, the amount of time required in the beam, to obtain the required neutron fluence. This will be based on beam type and beam flux. Some suitable neutron beam test facilities are included in Annex B.

<https://standards.iteh.ai/catalog/standards/sist/cad3fc11-37a6-4eb5-91e8-152b49a5ada0/iec-60749-44-2016>

<https://standards.iteh.ai/catalog/standards/sist/cad3fc11-37a6-4eb5-91e8-152b49a5ada0/iec-60749-44-2016>

6 Evaluation

6.1 Measurement and failure rate estimation

The set-up of DUTs and the measuring system are the same as for the other accelerated tests.

The effective SEU cross section σ_{eff} over the specific range of energy can be defined as follows:

$$\sigma_{eff} = \frac{N_{err}}{\Phi(E_{min}, E_{max})} \quad (1)$$

where

N_{err} is total number of errors counted per device;

$\Phi(E_{min}, E_{max})$ is the total fluence in the energy range from E_{min} to E_{max} . (neutron \times cm⁻²).

On the condition that the shape of the white neutron spectrum is close enough to the field spectrum, Soft error rate (SER) or single event effect rate (SEE rate) can be estimated by

$$SER = \sigma_{eff} \phi_{field}(E_{min}, E_{max}) \quad (2)$$

where

$\phi_{field}(E_{min}, E_{max})$ is the neutron flux in the field (neutron.cm⁻².s⁻¹).